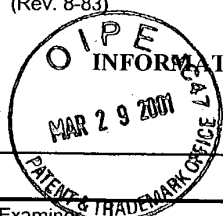


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Applicants: Shunpei YAMAZAKI et al.

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FOREIGN PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Country	Class	Subclass	Translation Yes No
Alr	58-091676	05/31/1983	JP			Full Eng

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

Examiner Initial	
Alr	Nakazawa et al., "17.3: Lightly Doped Drain TFT Structure for Poly-Si LCDs", 1990, pp. 311-314, SID 90 Digest
Alr	Morozumi et al., "5.2 Low Temperature Processed Poly Si TFT and it's Application to Large Area LCD", 1986, pp. 196-199, R&D Dept. Seiko Epson Corp. Nagano, Japan Dislay
Alr	325105, "Enhanced Adhesion to Glass Substrates Using Tantalum Oxide Adhesion Layer", May 1991, pp. 369, Research Disclosure, No. 325, Havant GB, XP229725
Alr	Ghandhi, "Silicon and Gallium Arsenide", 1983, pp. 401-411, VLSI Fabrication Principles

Examiner

Hanna Schultz

Date Considered

8/29/00

*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

03/19/2001